

Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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过往专利使用部分

理论上的过往专利使用债务 (“PUTL”)
根据预设的专利许可费率来确定被许可人 理论上
的过往专利使用债务金额

Past Use Theoretical Liability (“PUTL”)

Determination of new licensee Past Use Theoretical
Liability based on the assumed royalty rate

Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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过往专利使用部分

理论上的过往专利使用债务 (“PUTL”) 根据预设的专利许可费率来确定被许可人 理论上的过往专利使用债务金额

Past Use Theoretical Liability (“PUTL”)
Determination of new licensee Past Use Theoretical Liability based on the assumed royalty rate

系数“W”用于确定 “过往专利使用应付金额” (“PULP”)

A liability coefficient “W” is used to determine the Past Use Liability Payable (“PULP”)

可许可市场的渗透率

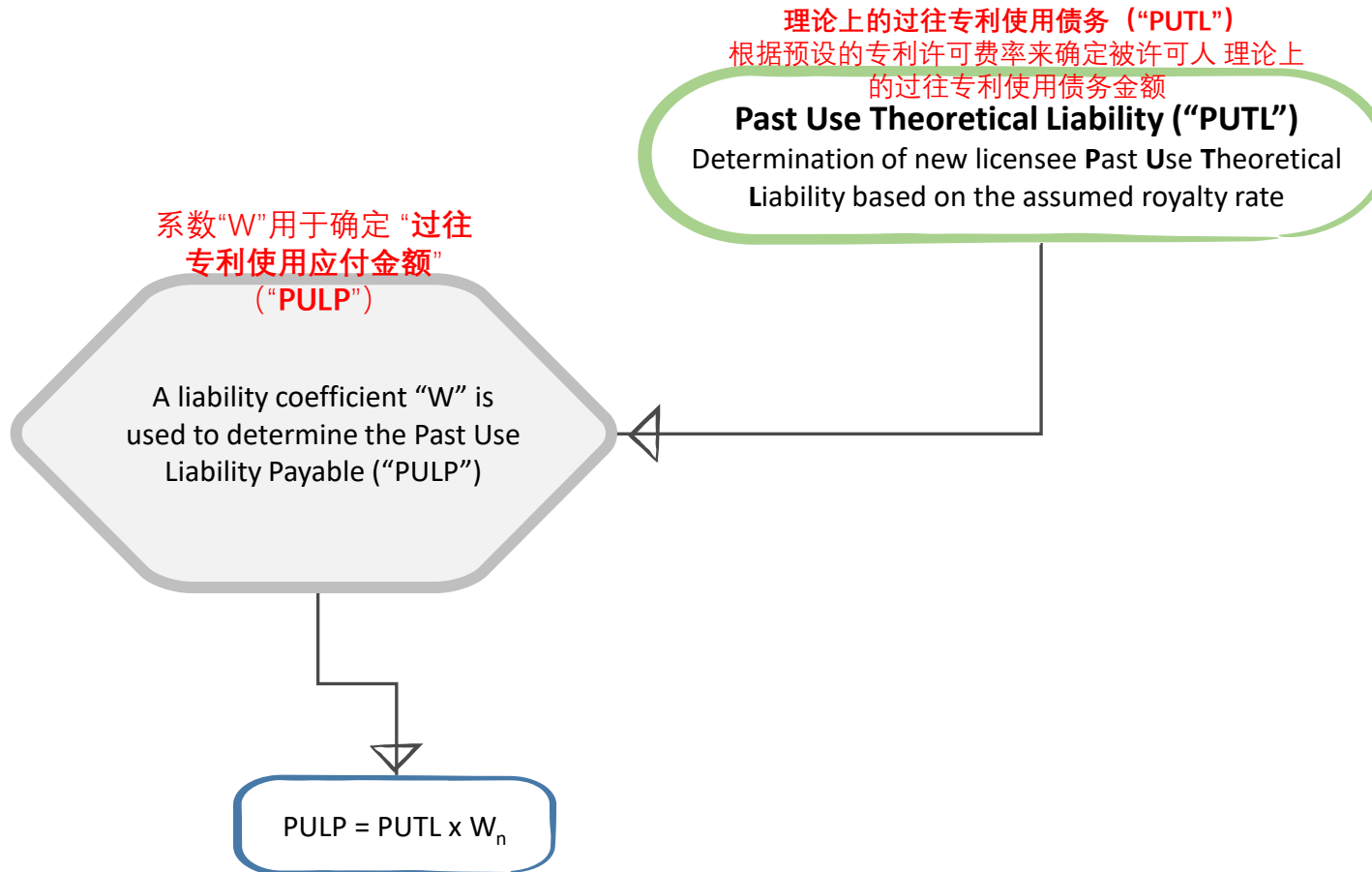
系数“W”

Licensable Market Penetration (“LMP”)	Coefficient W (“W”)
0% ≤ LMP < 5%	10%
5% ≤ LMP < 15%	15%
15% ≤ LMP < 25%	30%
25% ≤ LMP < 35%	45%
35% ≤ LMP < 45%	60%
45% ≤ LMP < 55%	80%
55% ≤ LMP	100%

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过往专利使用部分

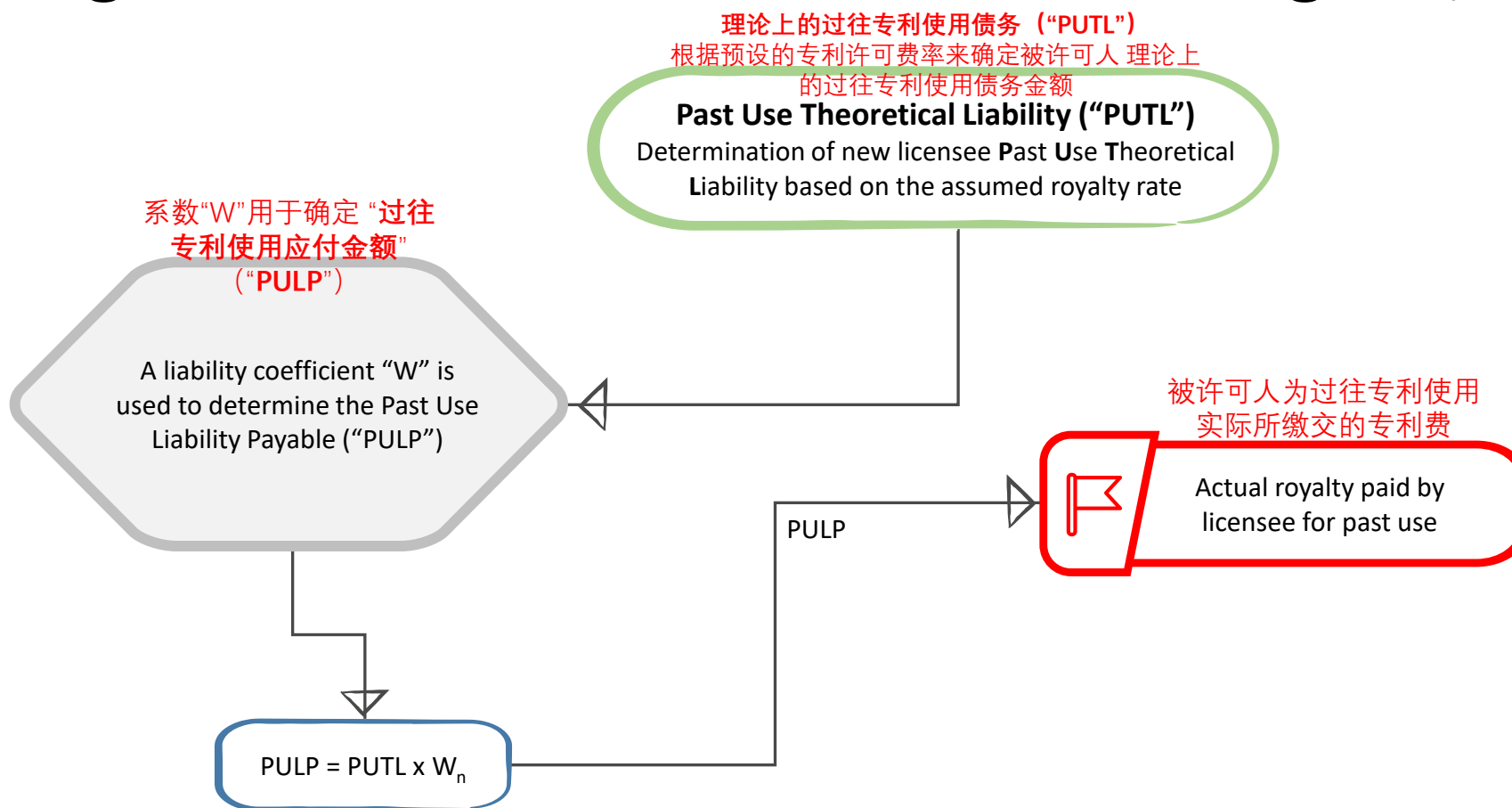


过往专利使用部分

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过往专利使用部分

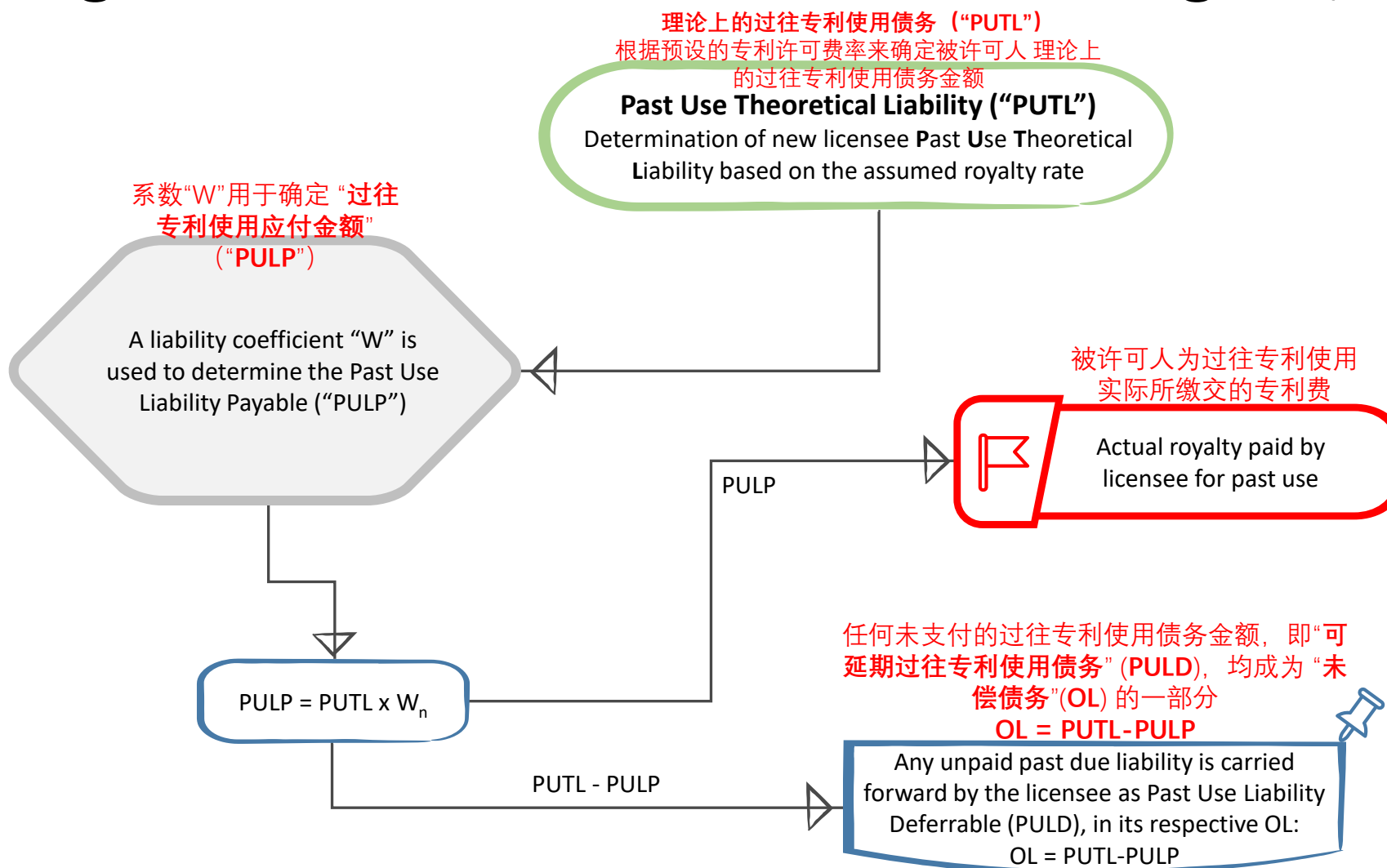


过往专利使用部分

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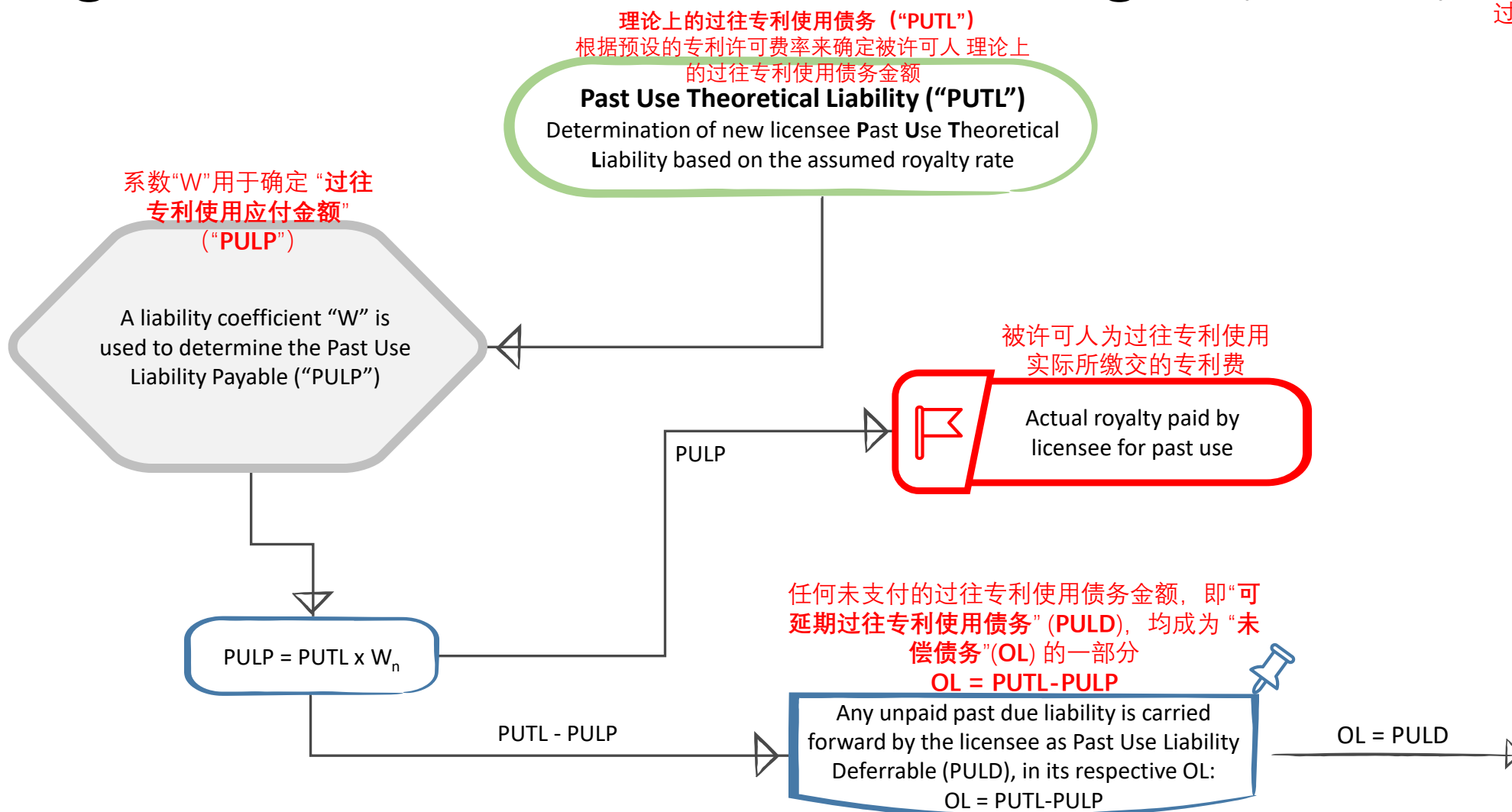
过往专利使用部分



Licensing Incentive Framework for Technologies (“LIFT”): Past Use

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过往专利使用部分



Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

理论上的计量专利使用债务 (“RRTL”)
每个季度基于预设的许可费率来确定

Running Royalty Theoretical Liability (“RRTL”)
based on the assumed royalty rate is determined in each
quarter

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

系数“W” 每季度确定一次。
W 用于确定“计量专利使用应付金额” (“RRP”) 和“可延期计量专利使用金额” (“RRD”)

理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定

A liability coefficient “W” is determined quarterly. W is used to determine both Running Royalty Payable (“RRP”) and Running Royalty Deferrable (“RRD”)

Running Royalty Theoretical Liability (“RRTL”)
based on the assumed royalty rate is determined in each quarter

可许可市场的渗透率

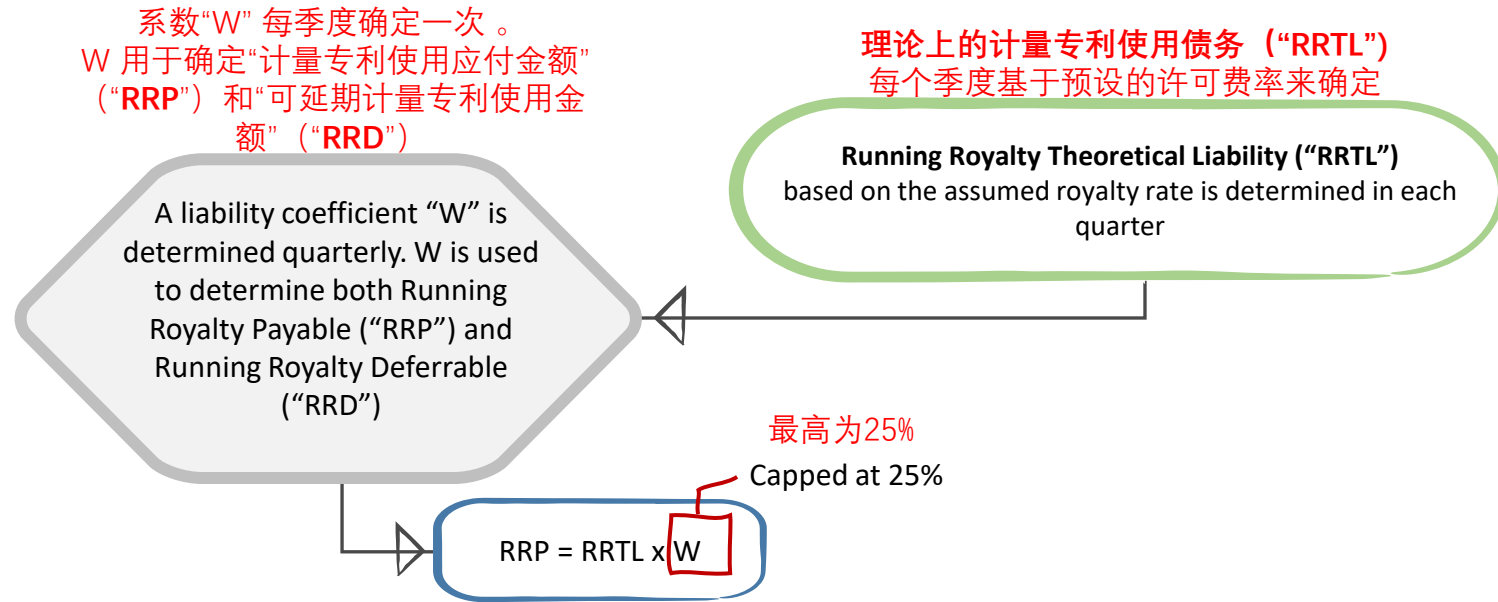
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Licensing Incentive Framework for Technologies (“LIFT”): Running

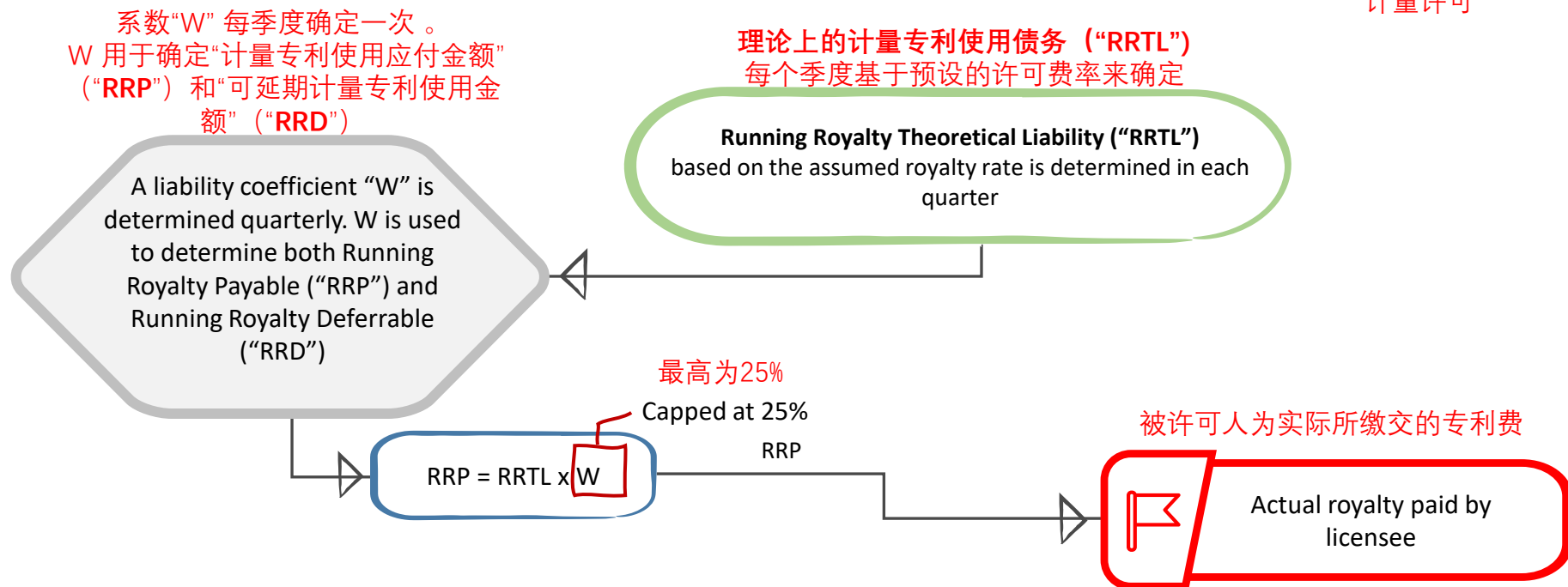
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计量许可



Licensing Incentive Framework for Technologies (“LIFT”): Running

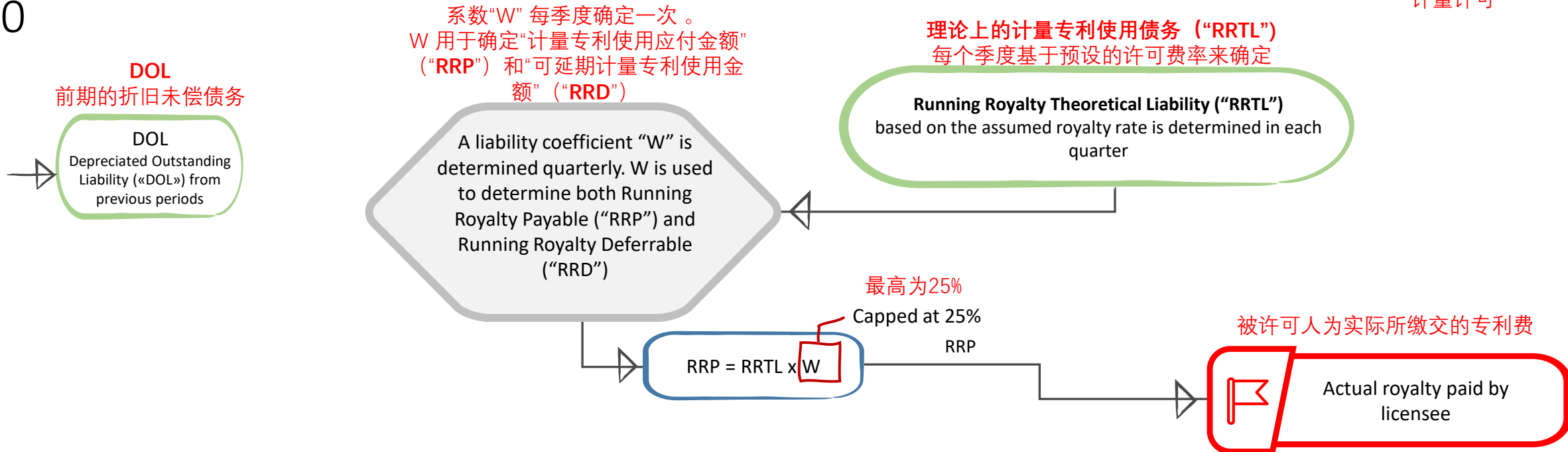
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Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可



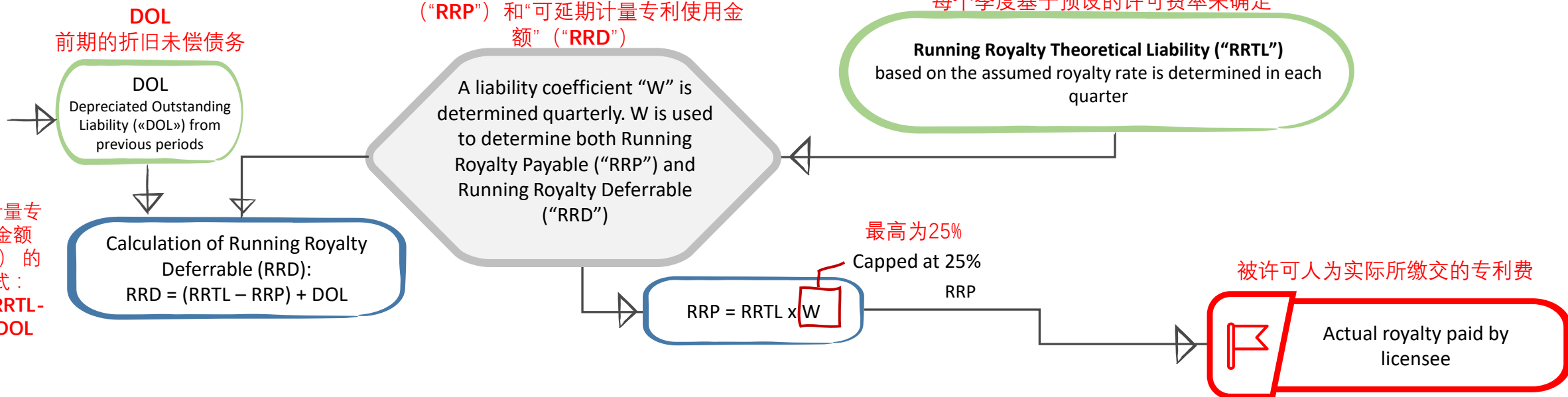
Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

系数“W” 每季度确定一次。
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理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定

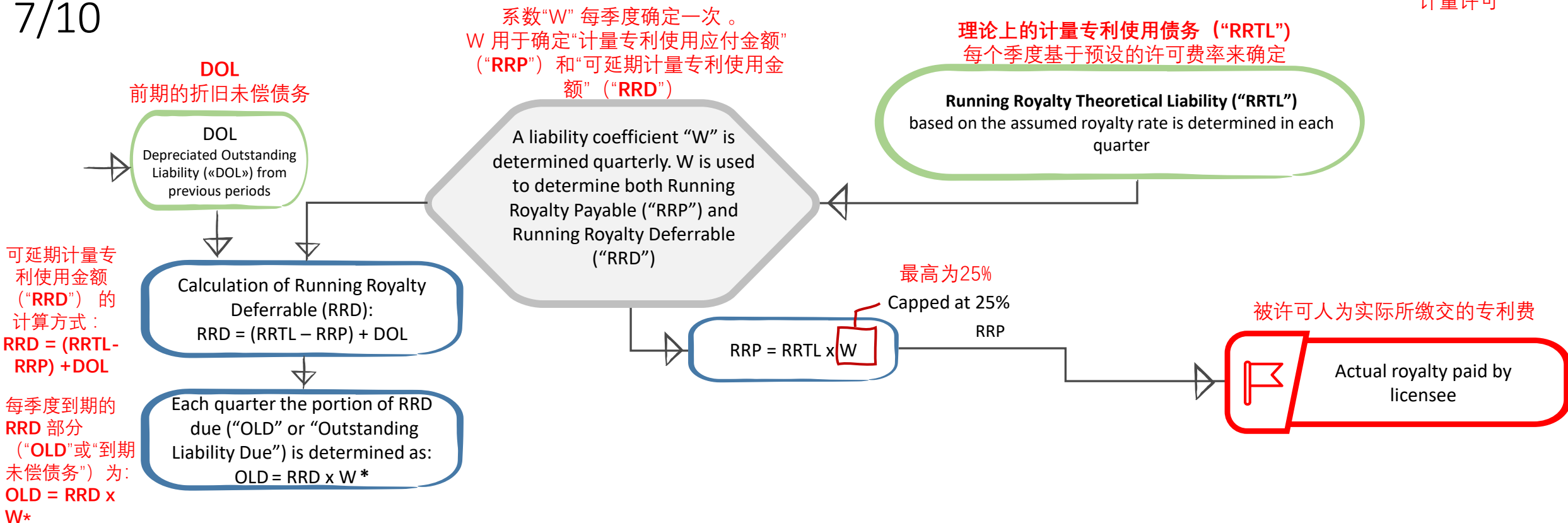


计量许可

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可



* The difference between RRD and OLD is deferred

* RRD 和 OLD 之间的差异被延期 计量许可

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可

系数“W” 每季度确定一次。
W 用于确定“计量专利使用应付金额” (“RRP”) 和“可延期计量专利使用金额” (“RRD”)

理论上的计量专利使用债务 (“RRTL”) 每个季度基于预设的许可费率来确定

DOL
前期的折旧未偿债务

Running Royalty Theoretical Liability (“RRTL”)
based on the assumed royalty rate is determined in each quarter

A liability coefficient “W” is determined quarterly. W is used to determine both Running Royalty Payable (“RRP”) and Running Royalty Deferrable (“RRD”)

可延期计量专利使用金额 (“RRD”) 的计算方式:
 $RRD = (RRTL - RRP) + DOL$

DOL
Depreciated Outstanding Liability («DOL») from previous periods

Calculation of Running Royalty Deferrable (RRD):
 $RRD = (RRTL - RRP) + DOL$

Each quarter the portion of RRD due (“OLD” or “Outstanding Liability Due”) is determined as:
 $OLD = RRD \times W$

Deferred amount:
 $OL = RRD - OLD$
延期金额: $OL = RRD - OLD$

最高为25%
Capped at 25%
RRP

$RRP = RRTL \times W$

被许可人为实际所缴交的专利费

Actual royalty paid by licensee

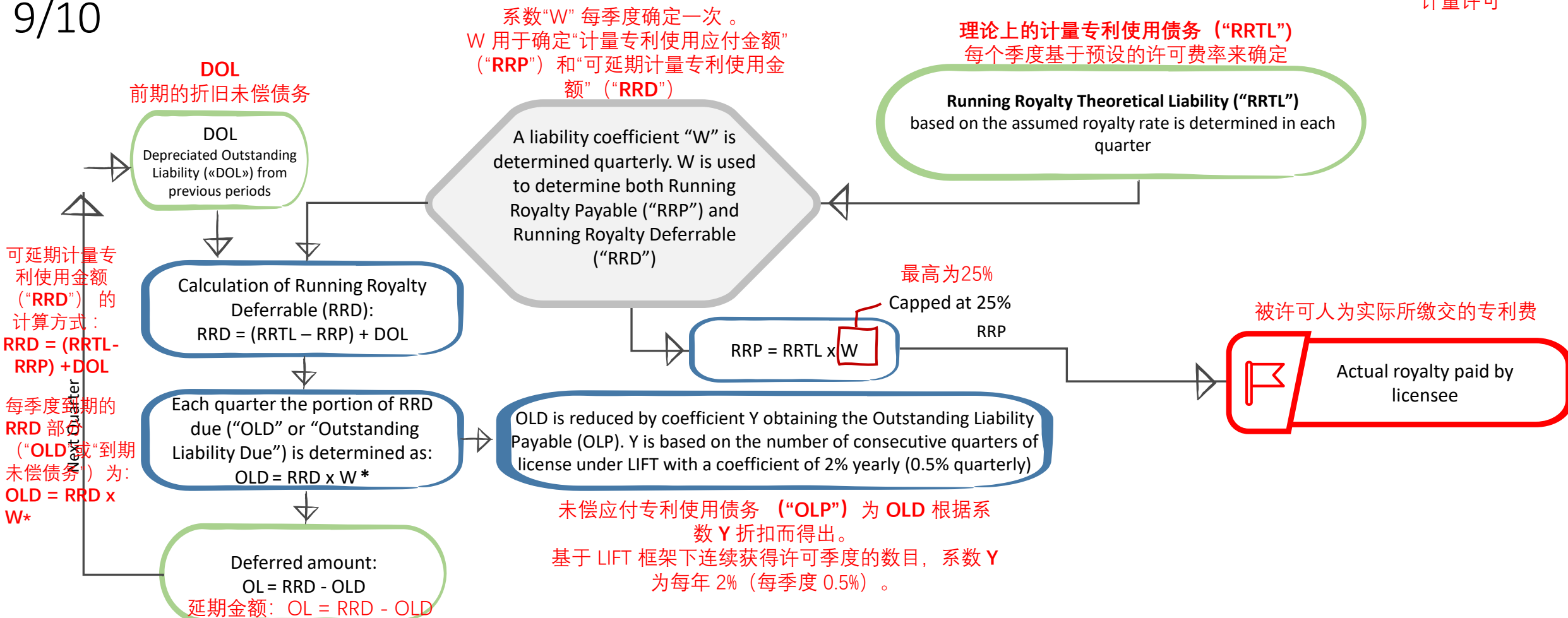
每季度到期的 RRD 部分 (“OLD”或“到期未偿债务”) 为:
 $OLD = RRD \times W$

* The difference between RRD and OLD is deferred
* RRD 和 OLD 之间的差异被延期 计量许可
Licensing Incentive Framework for Technologies – LIFT: Running

Licensing Incentive Framework for Technologies (“LIFT”): Running

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计量许可



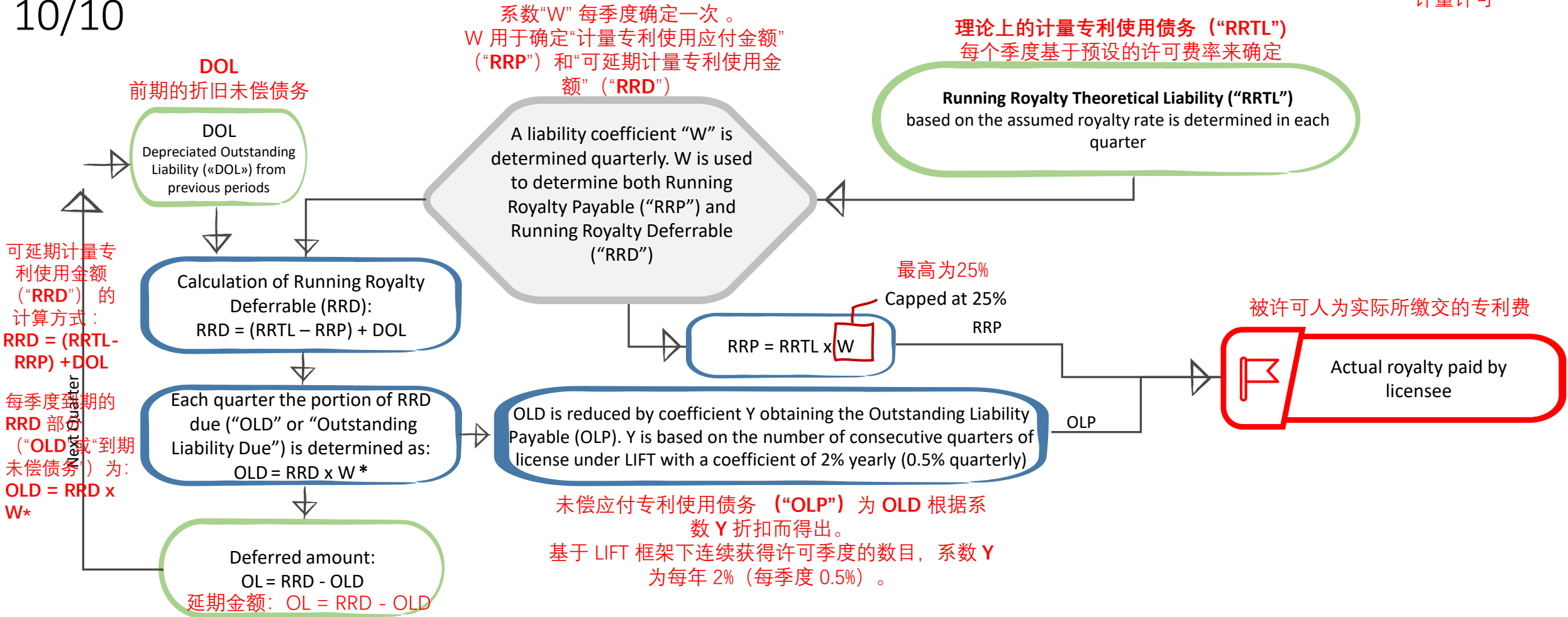
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Licensing Incentive Framework for Technologies (“LIFT”): Running

计量许可

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* The difference between RRD and OLD is deferred

* RRD 和 OLD 之间的差异被延期 计量许可